

## **S3-1.6**

### **Fabrication MEMS Platform for Sensors Applications by Laser Micro Engraving**

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The target of this work is the demonstration of advanced novel approaches able to provide rapid prototyping by using laser technology ceramic MEMS platforms for chemical sensor operating under harsh environmental conditions and, on the other hand, to assure microhotplate stable at high temperature, which can be used for the deposition of high working temperature gas sensing materials, for example, oxides of tin, gallium, zirconium and hafnium. As substrate ceramic material in work using alumina oxide.